## **TECHNICAL SPEC FOR Wet processing system**

System Model: 10501 LAM Ontrak Synergy

Wafer size: 6inch

Process: cleaning, after tungsten & process after CMP

Chemicals used: DIwater & NH4OH

Wafer material: Si

SMIF: NO

Input station: installed & water spray available

Brush module: part number 12-8800-167

Hastelloy carriage: installed

Process bowl: Sink, spin station 13inch

Heat lamp yes

Edge gripping unload handler: YEs

Dual sensor blade loader: yes

Output station: part number12-8872-196

Pumps: NA

**Controllers: Gespac** 

SECS: secs communication installed

Vintage:

Missing parts: none

**Defected parts: none** 

Software: 2.3.8

## **Operating system: OS-9**

## **Photos to Collect**

- All 4 sides
- Process module
- Control panel
- Robot
- Chemical cannisters
- Gauges/Valves
- Pumps
- Inside all cabinets (boards, electronics and chemicals)
- Serial plate
- Spare parts, manuals (if any)